

Sakari Sintonen

List of Publications by Year in descending order

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32
papers

698
citations

623188

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32
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docs citations

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times ranked

1139
citing authors

#	ARTICLE	IF	CITATIONS
1	Aluminum oxide from trimethylaluminum and water by atomic layer deposition: The temperature dependence of residual stress, elastic modulus, hardness and adhesion. <i>Thin Solid Films</i> , 2014, 552, 124-135.	0.8	155
2	Thermal and plasma enhanced atomic layer deposition of SiO ₂ using commercial silicon precursors. <i>Thin Solid Films</i> , 2014, 558, 93-98.	0.8	66
3	Preparation of deep UV transparent AlN substrates with high structural perfection for optoelectronic devices. <i>CrystEngComm</i> , 2016, 18, 3488-3497.	1.3	62
4	Defects in Single Crystalline Ammonothermal Gallium Nitride. <i>Advanced Electronic Materials</i> , 2017, 3, 1600496.	2.6	40
5	Aluminum oxide/titanium dioxide nanolaminates grown by atomic layer deposition: Growth and mechanical properties. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2017, 35, .	0.9	38
6	Synchrotron radiation x-ray topography and defect selective etching analysis of threading dislocations in GaN. <i>Journal of Applied Physics</i> , 2014, 116, 083504.	1.1	37
7	Diamond-like carbon (DLC) thin film bioelectrodes: Effect of thermal post-treatments and the use of Ti adhesion layer. <i>Materials Science and Engineering C</i> , 2014, 34, 446-454.	3.8	30
8	X-ray reflectivity characterization of atomic layer deposition Al ₂ O ₃ /TiO ₂ nanolaminates with ultrathin bilayers. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2014, 32, .	0.9	28
9	Thermal conductivity of amorphous Al ₂ O ₃ /TiO ₂ nanolaminates deposited by atomic layer deposition. <i>Nanotechnology</i> , 2016, 27, 445704.	1.3	27
10	Microscratch testing method for systematic evaluation of the adhesion of atomic layer deposited thin films on silicon. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2016, 34, .	0.9	21
11	Large-area analysis of dislocations in ammonothermal GaN by synchrotron radiation X-ray topography. <i>Applied Physics Express</i> , 2014, 7, 091003.	1.1	20
12	Incorporation and effects of impurities in different growth zones within basic ammonothermal GaN. <i>Journal of Crystal Growth</i> , 2016, 456, 43-50.	0.7	20
13	Effect of growth temperature on the epitaxial growth of ZnO on GaN by ALD. <i>Journal of Crystal Growth</i> , 2014, 398, 18-22.	0.7	19
14	Mechanical and optical properties of as-grown and thermally annealed titanium dioxide from titanium tetrachloride and water by atomic layer deposition. <i>Thin Solid Films</i> , 2021, 732, 138758.	0.8	17
15	Analysis of threading dislocations in void shape controlled GaN re-grown on hexagonally patterned mask-less GaN. <i>Journal of Crystal Growth</i> , 2012, 344, 59-64.	0.7	14
16	Defect structure of a free standing GaN wafer grown by the ammonothermal method. <i>Journal of Crystal Growth</i> , 2014, 406, 72-77.	0.7	13
17	Nanotribological, nanomechanical and interfacial characterization of atomic layer deposited TiO ₂ on a silicon substrate. <i>Wear</i> , 2015, 342-343, 270-278.	1.5	13
18	Evolution of impurity incorporation during ammonothermal growth of GaN. <i>Journal of Crystal Growth</i> , 2016, 456, 51-57.	0.7	13

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19	Patterning of sapphire/GaN substrates. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2011, 8, 1509-1512.	0.8	11
20	An investigation of structural properties of GaN films grown on patterned sapphire substrates by MOVPE. <i>Physica B: Condensed Matter</i> , 2009, 404, 4911-4915.	1.3	8
21	Synchrotron radiation X-ray topography and X-ray diffraction of homoepitaxial GaN grown on ammonothermal GaN. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2012, 9, 1630-1632.	0.8	7
22	Tribological properties of thin films made by atomic layer deposition sliding against silicon. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , 2018, 36, .	0.9	7
23	Evaluation of critical thickness of Ga _{0.98} N _{0.02} layer on GaP substrate by synchrotron X-ray diffraction topography. <i>Thin Solid Films</i> , 2013, 534, 680-684.	0.8	5
24	Top-seeded solution growth of SrTiO ₃ single crystals virtually free of mosaicity. <i>Journal of Crystal Growth</i> , 2017, 468, 305-310.	0.7	5
25	Characterization of InGaN/GaN and AlGaIn/GaN superlattices by X-ray diffraction and X-ray reflectivity measurements. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2010, 7, 1790-1793.	0.8	4
26	MOCVD growth and characterization of near-surface InGaN/GaN single quantum wells for non-radiative coupling of optical excitations. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2012, 9, 1667-1669.	0.8	4
27	Synchrotron radiation X-ray topography and defect selective etching analysis of threading dislocations in halide vapor phase epitaxy GaN crystal grown on ammonothermal seed. <i>Japanese Journal of Applied Physics</i> , 2019, 58, SCCB19.	0.8	4
28	X-ray diffraction study of GaN grown on patterned substrates. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2011, 8, 1524-1527.	0.8	2
29	Effect of GaN cap thickness on carrier dynamics in InGaN quantum wells. <i>Physica Status Solidi C: Current Topics in Solid State Physics</i> , 2012, 9, 727-729.	0.8	2
30	Fabrication of GaN structures with embedded network of voids using pillar patterned GaN templates. <i>Journal of Crystal Growth</i> , 2013, 370, 42-45.	0.7	2
31	Analysis of Dislocations Generated during Metal-Organic Vapor Phase Epitaxy of GaN on Patterned Templates. <i>Japanese Journal of Applied Physics</i> , 2013, 52, 01AF01.	0.8	2
32	Synchrotron X-ray diffraction topography study of bonding-induced strain in silicon-on-insulator wafers. <i>Thin Solid Films</i> , 2016, 603, 435-440.	0.8	2